

.3	U	17		Issue Date	Pages	Title 🤼 📜 .		Current XRef	Retrieval Clas	177.00
		ত	US 6001309 A	19991214	17	Jet droplet device	422/100	347/19; 347/85;		Gam
		∀	US 6618850 B2	20030909	24	Inspection method and inspection system using charged particle bea	716 <i>1</i> 20	716/19; 716/21		Nish
1, 5		⊡	US 6091249 A	20000718	22	Method and apparatus for detecting defects in wafers	324/751	324/750; 324/754;		Talb et al.
12.7	П	⊘	US 5597459 A	19970128	15	Magnetron cathode sputtering method and apparatus	204/192.12	204/298.09; 204/298.11;		Altsi
		区	US 5482611 A	19960109	16	Physical vapor deposition employing ion extraction from a pla	204/298.17	204/192.12; 204/298.05;		Helm
	Г	R	US 4842703 A	19890627	20	Magnetron cathode and method for sputter coating	204/192.12	204/298.18		Clas
		Þ	US 4728862 A	19880301	6	A method for achieving ignition of a low voltage gas discharge device	315/111.01	313/161; 313/231.31;		Kova
1		F)	US 4423355 A	19831227	28	lon generating apparatus	315/111.81	250/426; 313/231.41;	,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,	Kage
1.0		ĮZ.	US 6602425 B2	20030805	20	Method for low cost water disinfection	210/744	210/748; 250/430;		Gad
		F.	US 5628895 A	19970513	8	Closed circuit for treating drinking water with UV treatment and filter	210/85	210/143; 210/192;		Zuch
		Þ	US 5717204 A	19980210	36	Inspecting optical masks with electron beam microscopy	250 / 310	250/306; 250/307;		Meis
		⊡	US 4862414 A	19890829	25	Optoelectronic recording tape or strip comprising photoconductive la	365/106	396/661; 428/689;		Kuel
	П	F	US 4745360 A	19880517	10	Electron-beam probe system utilizing test device having interdigi	324/751	250/310; 250/492.2;		Rein
		区	US 5560543 A	19961001	24	Heat-resistant broad-bandwidth liquid droplet generators	239/102.2	239/135; 310/331;		Smit
		M	US 4845512 A	19890704	7	Drop deflection device and method for drop marking systems	347/77	239/690		Arw
	Г	R.	US 4735364 A	19880405	10	Electrostatic spray head	239/690.1	239/691; 239/708		Mar
44		E.	US 4579279 A	19860401	7	Electrostatic sprayers	239/3	239/703		Mar
}		区	US 4555712 A	19851126	12	Ink drop velocity control system	347/7	347/89; 73/861		Arw
) 👸	C	⊠	US 5903004 A	19990511	9	Energy dispersive X-ray analyzer	250/310	250/397; 250/399:		Kosł
) (C	Ŋ.	US 4520264 A	19850528	10	Electron microscope	250/311	250/396ML; 250/398	**************************************	Tsur
		덛	US 5519216 A	19960521	11	Electron-optical imaging system having controllable elements	250/311	250/307		Beni
2 47	C	R	US 5412209 A	19950502	29	Electron beam apparatus	250/310	250/396ML	4	Otak
3	Г	₽.	US 6569319 B2	20030527	41	UV light Intensity detector in a water treatment system	210/85	210/192; 250/474.1;	5	Kuer

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